What is the right LED epiwafer strategy for mass production of micro LED displays?

Burkhard Slischka, CEO and co-founder ALLOS Semiconductors International Micro LED Display Conference 2019, Taipei, 29th August 2019







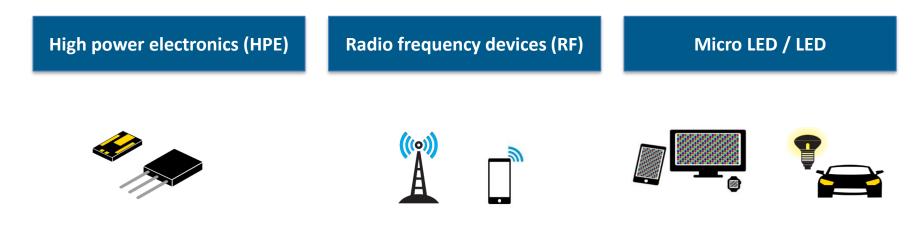
No need to take photos – write me to get your copy bs@allos-semiconductors.com

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- 1. Introduction to ALLOS Semiconductors
- 2. How to make micro LED displays a mass market reality?
- 3. Manufacturing readiness of ALLOS' epiwafer technology
- 4. How to work with ALLOS



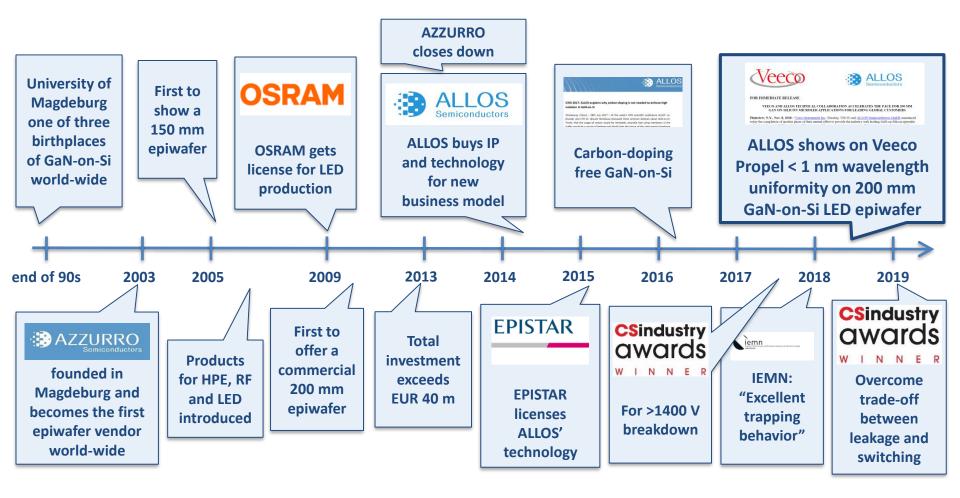
ALLOS develops and offers GaN-on-Si technology, which is the key enabler for three fast-growing markets



GaN-on-Si enables more energy-efficient, less complex and smaller high power electronic (HPE) devices from existing silicon lines GaN-on-Si provides higher performance, smaller, more energy efficient and lower cost RF devices, for 5G base-stations, smartphones, CATV, IoT and other RF applications Only GaN-on-Si allows super-uniform, large diameter, CMOS-compatible 1 bin[®] epiwafers needed for large-scale micro LED display production



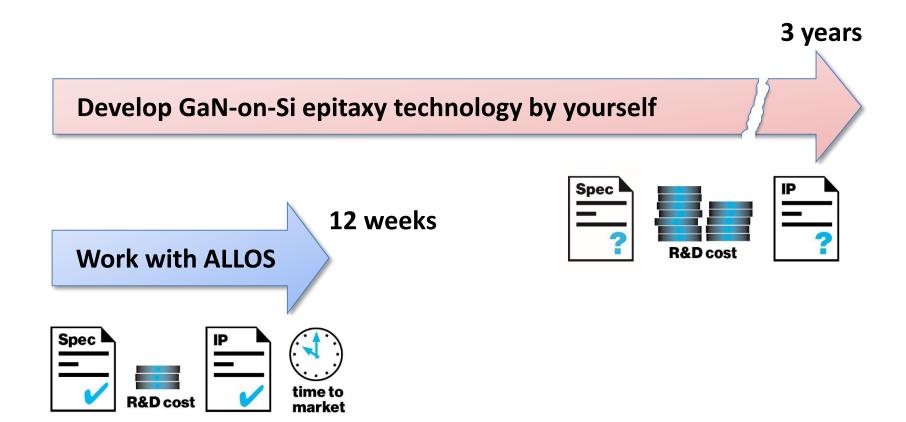
ALLOS* is a leader in GaN-on-Si with 15 years track-record



* ALLOS and its predecessor-company AZZURRO



Technology Transfer is the core of our business offer

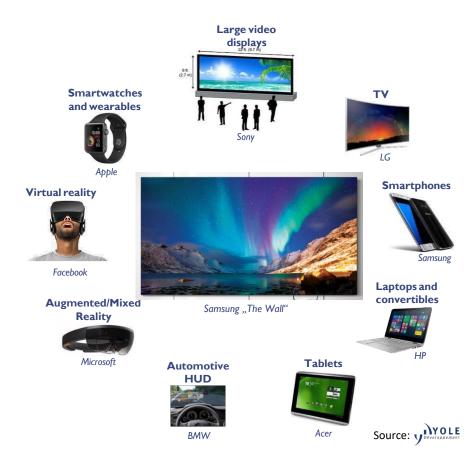




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Micro LED displays: Big advantages over LCD and OLED rivals...



- Perfect black, brightness and contrast
- Displays readable even in sunlight
- High resolution and pixel density
- More accurate and vivid colors
- ✓ Longer battery runtime
- ✓ Fast refresh rates
- ✓ Wide viewing angles
- Curved and flexible backplanes
- Integration of sensors within display
- Long lifetime, environmental stability
- Can be integrated into window glass, fabric, building structures or other materials

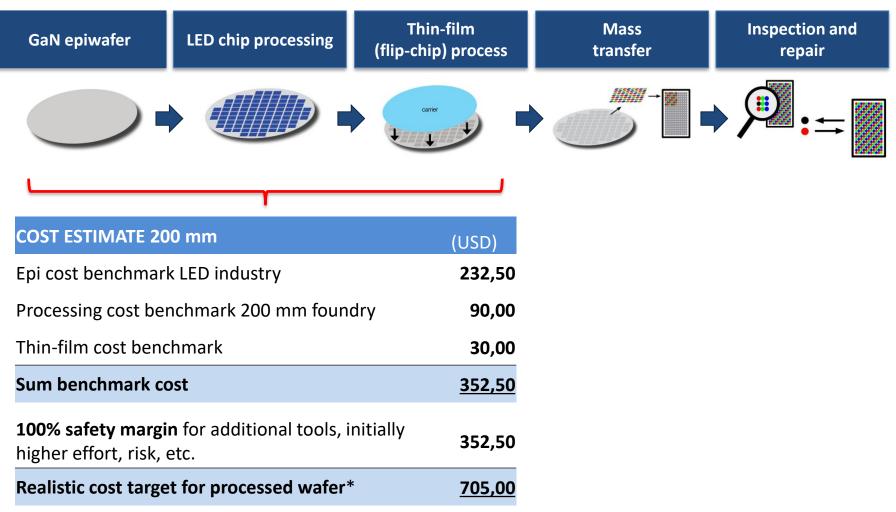


... but one big challenge prevents mass market break-through



ALLOS Semiconductors

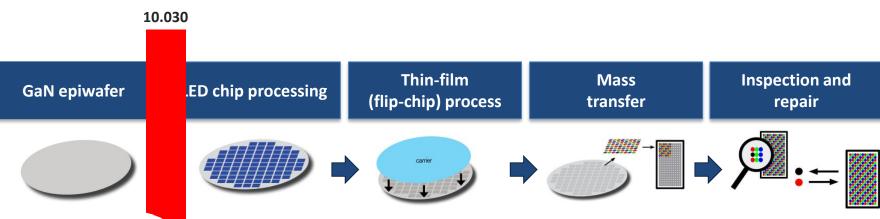
Where is this cost problem coming from? (1)

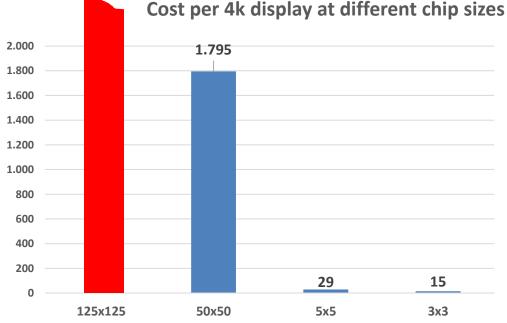


* Source: ALLOS' research; assuming volume production; cost estimate based on blue LED chips on 200 mm wafer ready to be transferred; assuming same area cost for green and red epiwafers



Where is this cost problem coming from? (2)





Chip sizes in μm ; see previous slide for assumptions

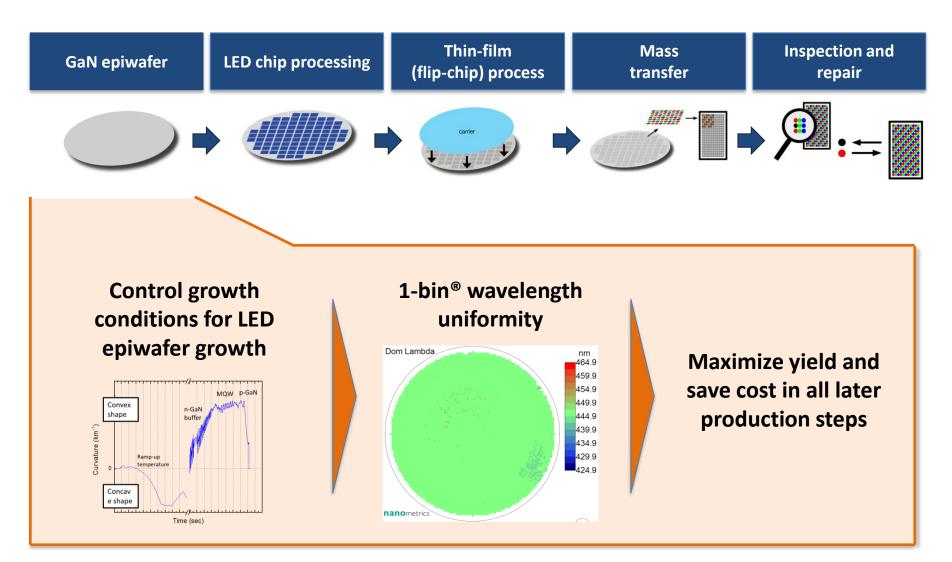
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emiconductors

- Even with 100 % safety margin processed micro LED wafers are cost competitive
- Increased usage of smaller chips will drive down cost
- The real challenge is yield
- ...and resulting cost in test, transfer and repair

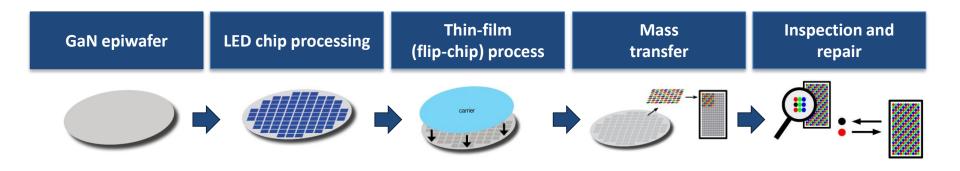


How to make micro LED displays a mass market reality? (1)





How to make micro LED displays a mass market reality? (2)



Move to larger epiwafer sizes to save cost along the entire value chain

- Better reactor area utilization on most multi-wafer chamber reactors
- Use latest generation single-wafer chamber reactors for 1-bin[®] wavelength uniformity
- Biggest cost effects are realized at LED chip processing and thin-film processing

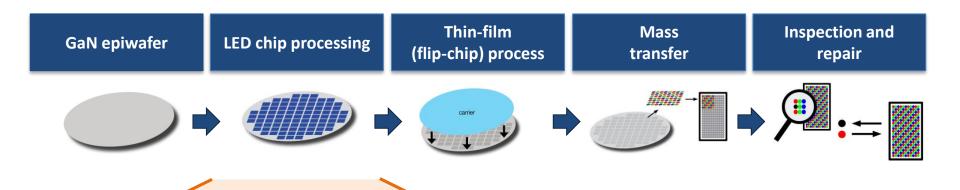


34 % better area utilization for 200 mm vs. 100 mm on G5+

For GaN-on-Si 200 mm is already available, path to 300 mm GaN-on-Si is open



How to make micro LED displays a mass market reality? (3)



High processing requirements for micro LEDs

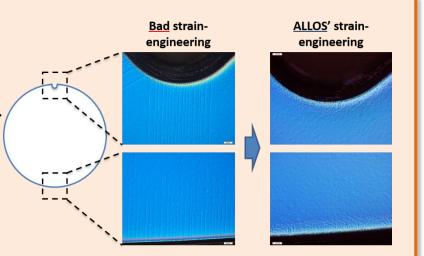
Precision, processing resolution, particles, etc.

Consider new sourcing models

- Either huge investments for dedicated new fabs...
- Or partner with e.g. low-cost CMOS foundries

Ensure that epiwafers meet requirements for low-cost and high yield processing lines

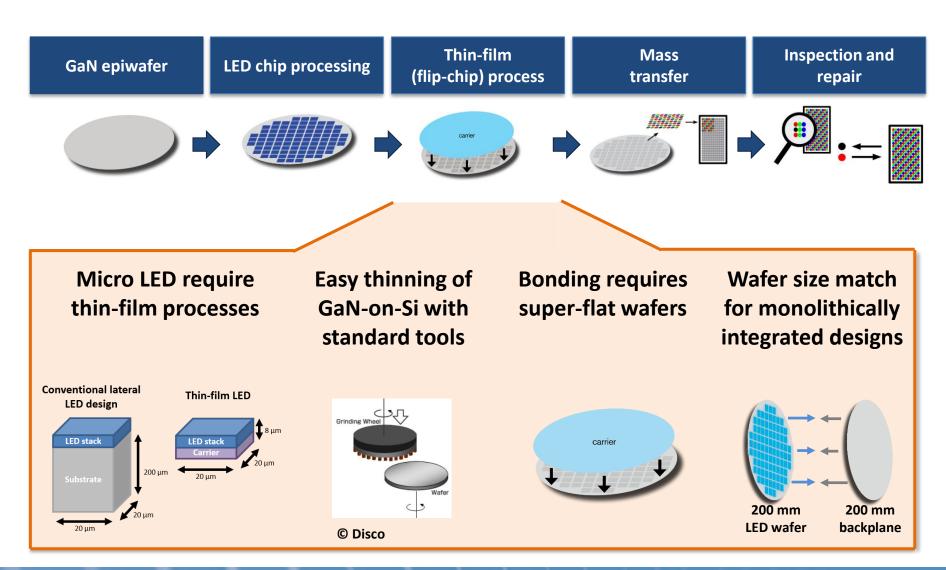
- Wafer cleanliness, thickness, no breakage, etc.
- Minimal wafer bow
- Large wafer diameter (200 or 300 mm)



ALLOS' 200 mm LED epiwafers crack-free even at the edge



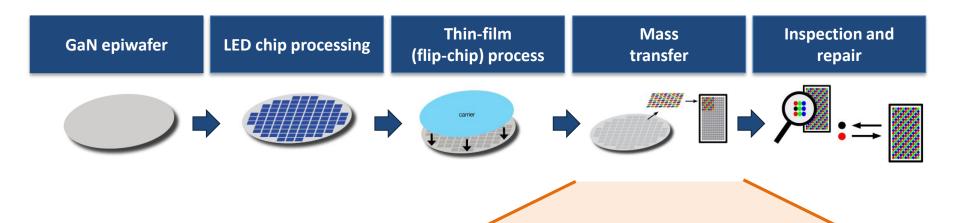
How to make micro LED displays a mass market reality? (4)





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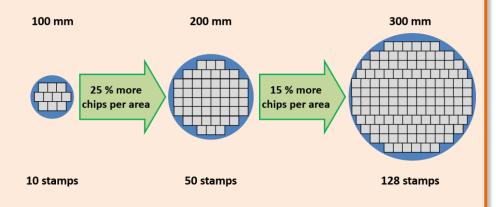
How to make micro LED displays a mass market reality? (5)



Multiple mass transfer methods have been already demonstrated

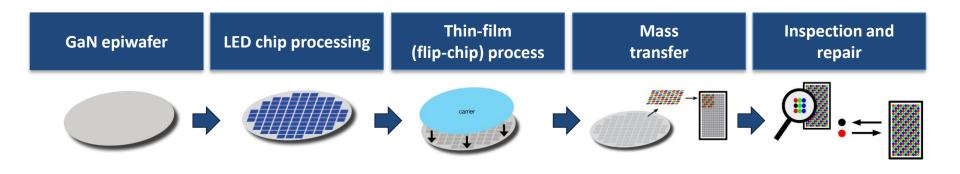
- Pick and place takes too long
- Binning is not an option
- All methods work with GaN-on-Si LED epiwafers

Transfer stamp based methods all benefit from larger epiwafers





How to make micro LED displays a mass market reality? (6)



Perfect displays required

- Consumers do not accept even one bad pixel
- Even at Six Sigma level 2,488 chips have to be repaired on a 4K display
 Even at Six Sigma level 2,488
 Even at Six S
- But to test and sort each of 25 million sub-pixels before transfer is very expensive

Two major approaches to solve this dilemma

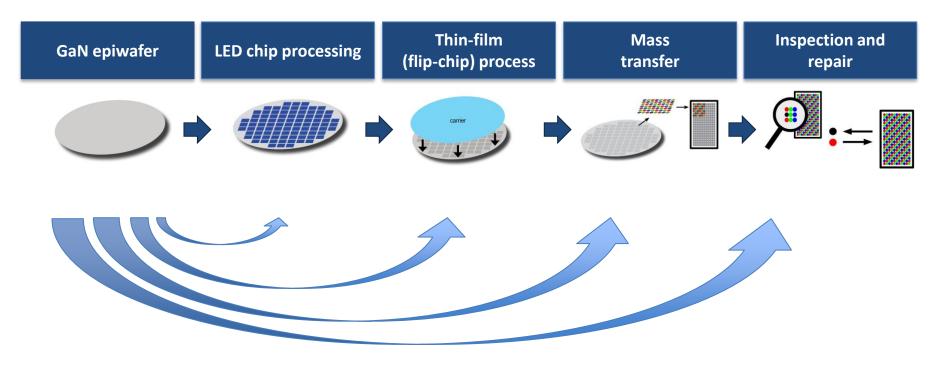
- A. "Blind printing"
- No testing, just transfer and "test" on display
- Repair on display (e.g. using redundancies)

- B. "Maximize % of KGD"
- In-line testing
- Transfer only known good dies / segments
- No or minimal repair needed

Both become cost-efficient only with super uniform epiwafer material



1-bin[®] epiwafer properties can maximize yield and save cost in all later production steps



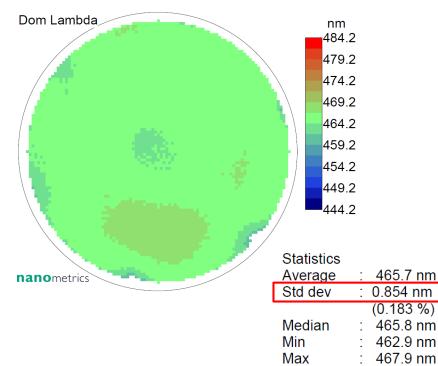
Epiwafer uniformity and quality is crucial for yield and cost in all later steps



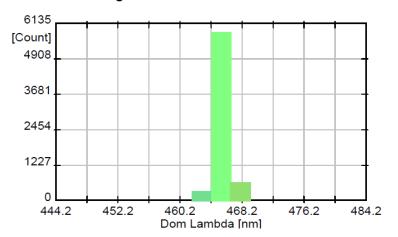
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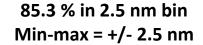


Record-breaking emission uniformity < 1 nm is achieved on 200 mm GaN-on-Si micro LED epiwafer



Dom Lambda Histogram

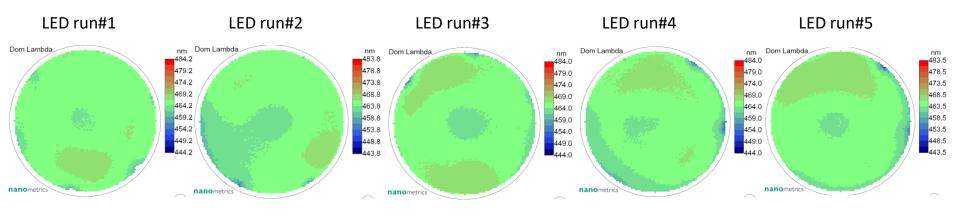




Result from customer project on Veeco Propel in summer 2018



The technology has excellent reproducibility (PL mapping)

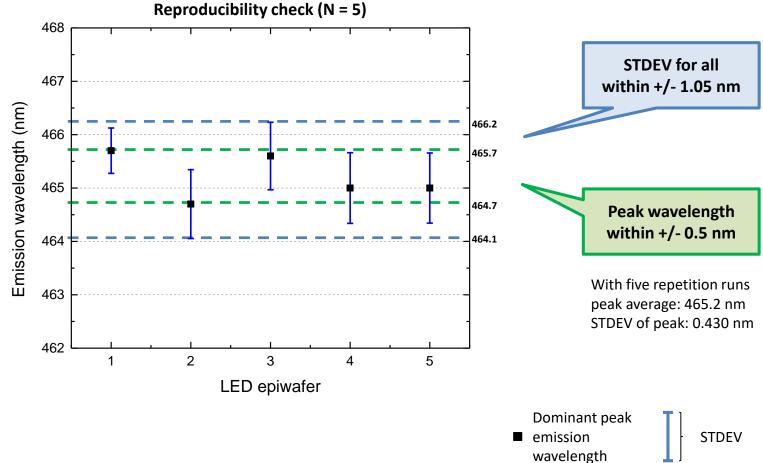


Statistics	Statistics	Statistics	Statistics	Statistics
Average : 465.7 nm	Average : 464.7 nm	Average : 465.6 nm	Average : 465.0 nm	Average : 465.0 nm
Std dev : 0.854 nm	Std dev : 1.290 nm	Std dev : 1.262 nm	Std dev : 1.323 nm	Std dev : 1.314 nm
(0.183 %)	(0.278 %)	(0.271 %)	(0.284 %)	(0.283 %) Median : 465.0 nm Min : 460.5 nm Max : 467.8 nm 10% cutoff : 463.3 nm 25% cutoff : 464.2 nm 75% cutoff : 465.8 nm 90% cutoff : 466.9 nm
Median : 465.8 nm	Median : 465.0 nm	Median : 465.6 nm	Median : 465.2 nm	
Min : 462.9 nm	Min : 460.6 nm	Min : 461.7 nm	Min : 460.6 nm	
Max : 467.9 nm	Max : 467.2 nm	Max : 468.4 nm	Max : 467.4 nm	
10% cutoff : 464.5 nm	10% cutoff : 462.9 nm	10% cutoff : 464.6 nm	10% cutoff : 463.3 nm	
25% cutoff : 465.1 nm	25% cutoff : 463.8 nm	25% cutoff : 464.6 nm	25% cutoff : 464.2 nm	
75% cutoff : 466.2 nm	75% cutoff : 465.6 nm	75% cutoff : 466.5 nm	75% cutoff : 466.1 nm	
90% cutoff : 466.7 nm	90% cutoff : 466.2 nm	90% cutoff : 467.3 nm	90% cutoff : 466.6 nm	

Result from customer project using the same recipe on Veeco Propel in summer 2018



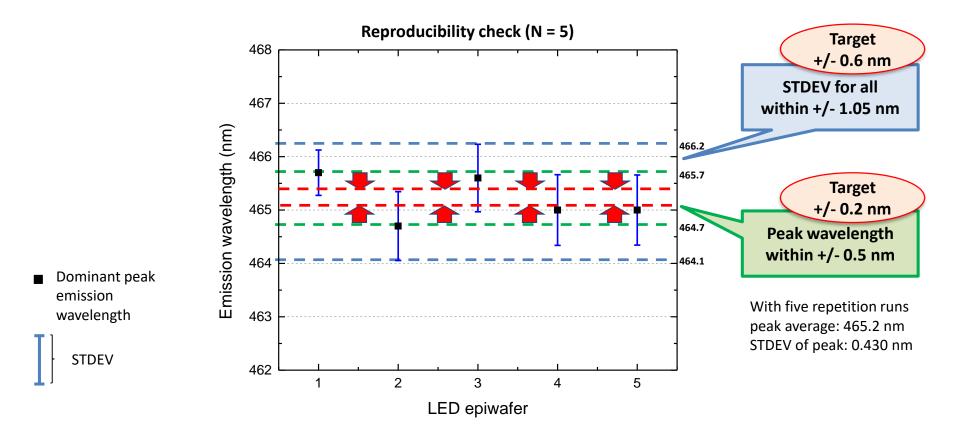
Peak emission wavelength is controlled within +/- 0.5 nm



Result from customer project using the same recipe on Veeco Propel in summer 2018



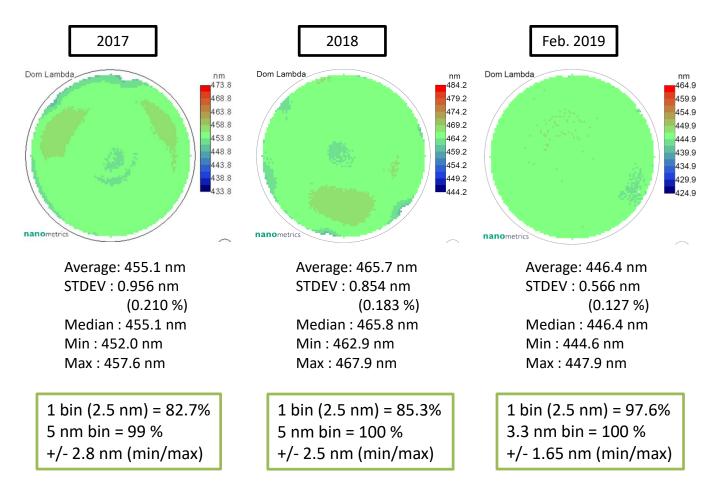
...with a development target of +/- 0.2 nm



Result from customer project using the same recipe on Veeco Propel in summer 2018



<u>Outlook:</u> Continued work shows more world record improvements for wavelength uniformity approaching the goal of +/- 1 nm



Project stage 2017: Achieving leading uniformity for 200 mm LED epiwafers (irrespective of substrate material)

Project stage 2018: Successfully achieving all needed production parameters at the same time with excellent wafer-to-wafer reproducibility

Project stage beginning of 2019:

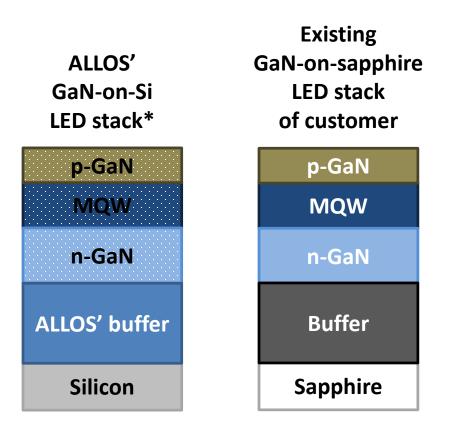
The current project focus is on further advancing the wavelength uniformity towards a true 1 bin® objective (+/- 1 nm); shown are intermediate results

Next will be work on achieving the new leading uniformity results with all production-relevant performance elements while guaranteeing excellent reproducibility ("made for manufacturability").

Result from customer project on Veeco Propel



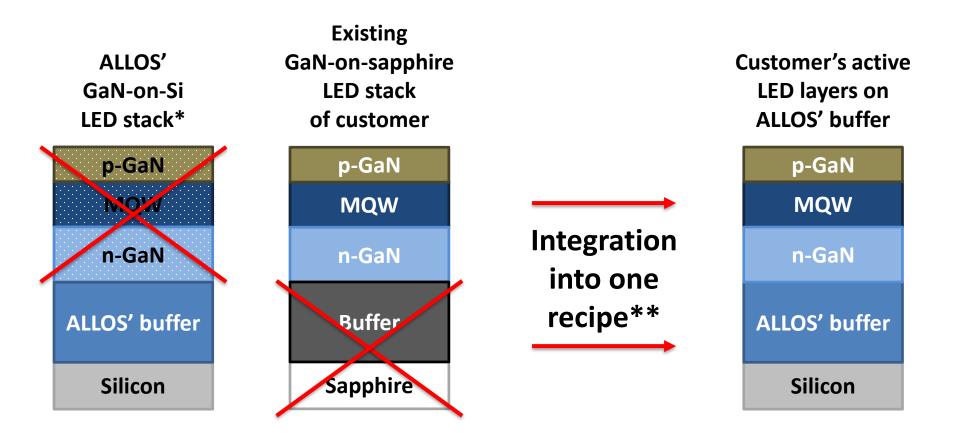
With only a few epi runs any existing active LED layer structure can be integrated on ALLOS' GaN-on-Si buffer



* Transferred to customer in Technology Transfer project



With only a few epi runs any existing active LED layer structure can be integrated on ALLOS' GaN-on-Si buffer



* Transferred to customer in Technology Transfer project

** By either joint team with ALLOS or independently by customer



...allowing the customer to benefit from the best of both technology sets

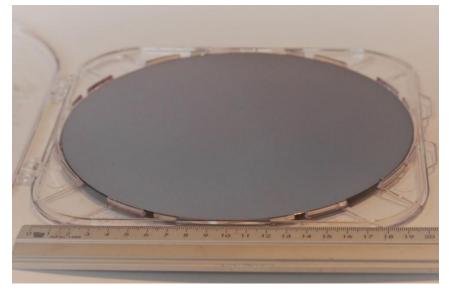
LED layers on **ALLOS'** buffer p-GaN Same performance (brightness, efficiency) on GaN-on-Si as on GaN-on-sapphire MQW Existing IP protection ٠ Preserve learnings for LED design / epi / processing interaction n-GaN Industry-leading GaN-on-Si performance with >15 years' of **ALLOS' buffer** technology development background Best wavelength uniformity (1-bin[®]) ٠ Silicon Large diameter, flat and CMOS-ready epiwafer

> DS clore

Customer's active

ALLOS' GaN-on-Si epiwafer fulfils <u>all</u> requirements for micro LED display mass production <u>at the same time</u>

200 mm GaN-on-Si epiwafer of ALLOS for micro LED



1 bin[®] wavelength uniformity

Existing MQW from on-sapphire can be easily integrated

Best GaN-on-Si crystal quality in the industry

- Same low defect level as on GaN-on-sapphire: TDD ~2 x 10⁸ cm⁻²
- Enables excellent LED performance

Large diameter and CMOS-ready

- 100 to 200 mm, next 300 mm
- 30 μm bow for 725 μm thickness at 200 mm
- No cracks, no residual strain



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Proposed steps of working with ALLOS

Step 1: Purchase sample package and evaluate ALLOS' LED epiwafers

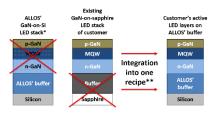
Step 2: Agree license and transfer ALLOS' technology to your* reactor

Step 3: Integrate your* light emitting epi-structure (optional)

Step 4: Optimize epi-stack for micro LED volume manufacturing (optional)









* Your or your partner's



Summary

- To become ready for volume production of micro LEDs the problem of insufficient yield needs to be solved
- Emission wavelength uniformity is the <u>biggest single driver</u> to achieve that objective
- The right (large diameter, high crystal quality, CMOS-ready) GaN-on-Si epiwafer technology can further <u>enable cost</u> <u>savings in all</u> following production <u>steps</u>
- ALLOS offers its GaN-on-Si technology for <u>licensing and</u> <u>technology transfer</u> and is open to work with you in your <u>long-term projects</u>



CSindustry awards





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